Atty Docket: 10829-8727US Inventors: David Palsulich et al.

Title: MICROFEATURE WORKPIECE PROCESSING SYSTEM FOR, E.G., SEMICONDUCTOR WAFER ANALYSIS



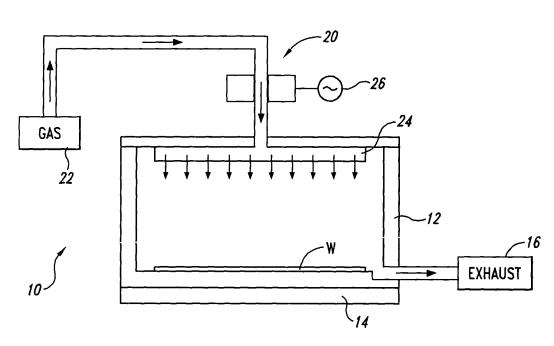


Fig. 1 (Prior Art)

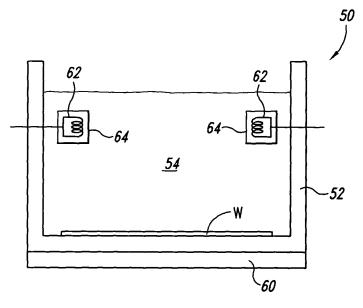


Fig. 2 (Prior Art)

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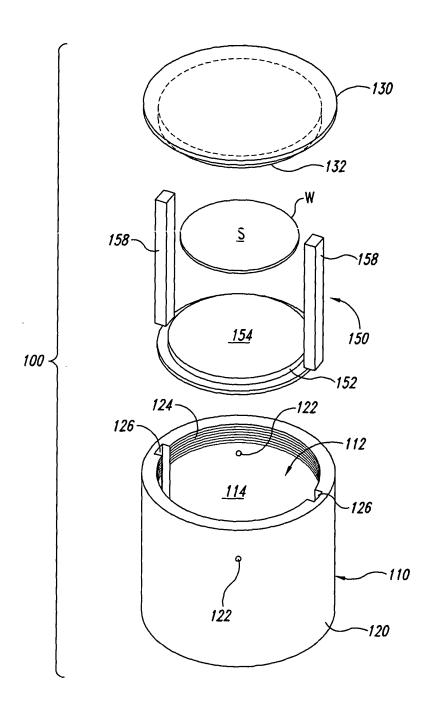


Fig. 3

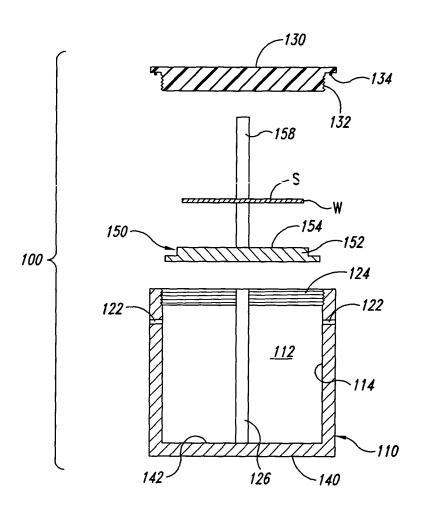


Fig. 4

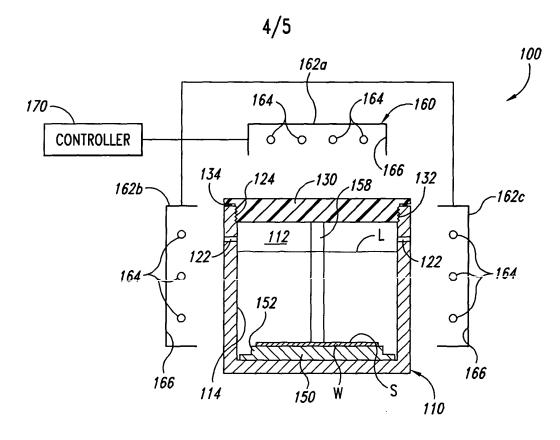


Fig. 5

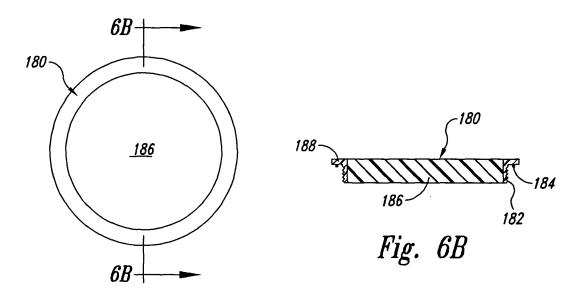


Fig. 6A

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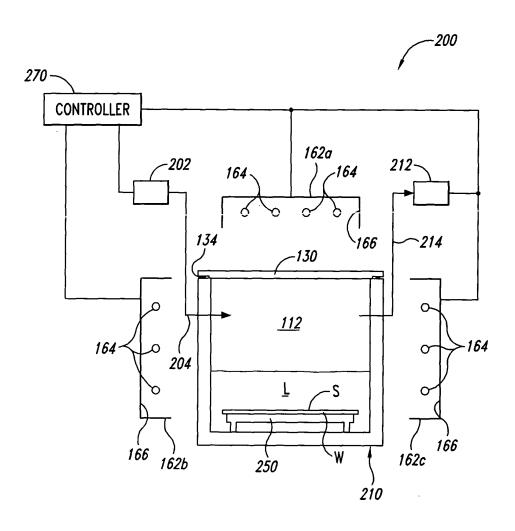


Fig. 7